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AMENDMENT TRANSMITTAL LETTER (Large Entity)

Applicant(s): Yoshirou Tsurugida

Docket No.

OKI.291

Serial No.

10/034,379

Filing Date

01/03/2002

Examiner

David Nhu

Group Art Unit

2818

Invention: **METHOD FOR SELECTIVELY OXIDIZING A SILICON WAFER**

MAR 24 2004

TO THE COMMISSIONER FOR PATENTS:

Transmitted herewith is an amendment in the above-identified application.

The fee has been calculated and is transmitted as shown below.

CLAIMS AS AMENDED

	CLAIMS REMAINING AFTER AMENDMENT	HIGHEST # PREV. PAID FOR	NUMBER EXTRA CLAIMS PRESENT	RATE	ADDITIONAL FEE
TOTAL CLAIMS	6 -	20 =	0 x	\$18.00	\$0.00
INDEP. CLAIMS	1 -	3 =	0 x	\$86.00	\$0.00
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					\$0.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT					\$0.00

- ☒ No additional fee is required for amendment.
- ☐ Please charge Deposit Account No. _____ in the amount of _____
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- ☐ Any additional filing fees required under 37 C.F.R. 1.16.
- ☐ Any patent application processing fees under 37 CFR 1.17.


Signature

Dated: **MARCH 24, 2004**

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Serial No. 10/034,379
OKI.291
Amendment dated March 24, 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent application of :
Yoshirou Tsurugida : Group Art Unit 2818
Serial No. 10/034,379 : Examiner David Nhu
Filed January 3, 2002 :

METHOD FOR SELECTIVELY OXIDIZING A SILICON WAFER

AMENDMENT

U.S. Patent and Trademark Office
2011 South Clark Place
Customer Window, **Mail Stop Non-Fee Amendment**
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

In response to the Office action of January 9, 2004, please amend the
above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which
begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.